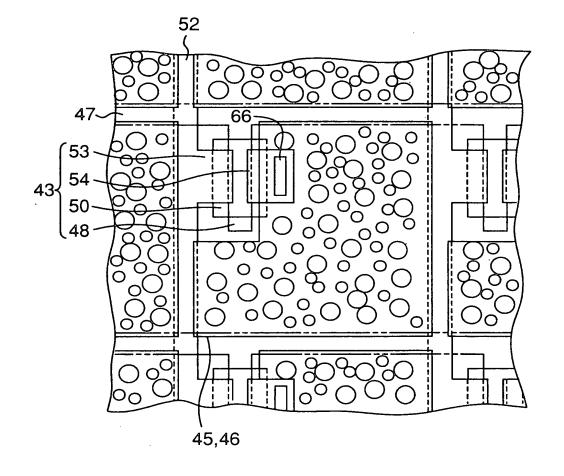
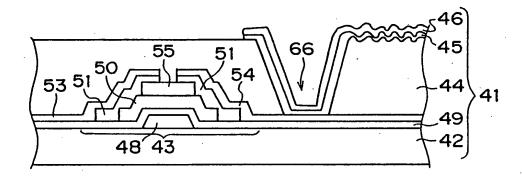
Fig. 1



1

Fig. 2A



Fi g. 2B

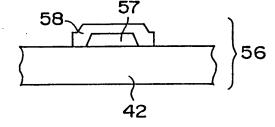
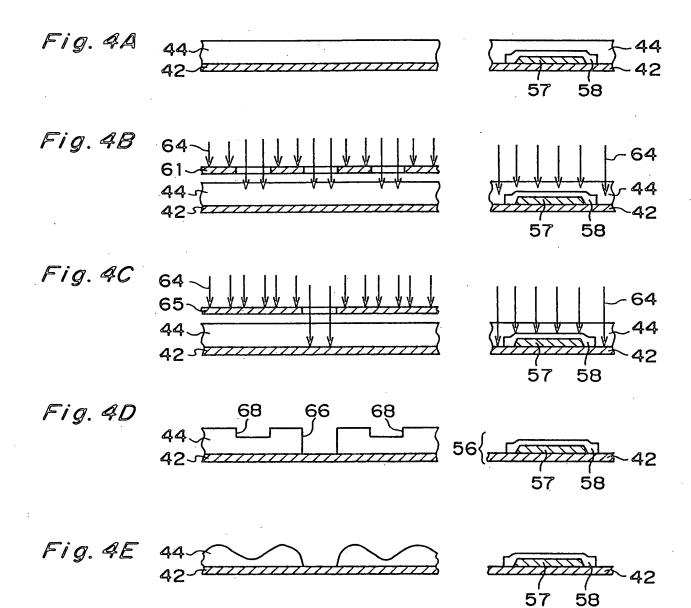


Fig. 3

	Ar Flow Rate	Ar Flow Rate N2 Flow Rate etch	ETCHING RATE (nm/min.)	PEEL TEAT RESULT	ADHESION	IING RATE (nm/min.) PEEL TEAT RESULT ADHESION N2 ATOM % BY AUGER SPECTROSCOPY
CONDITION1	100	0	754	100/100	×	
CONDITION2	100	20	648	48/100	Δ	2
CONDITIONS	100	40	562	0/100	0	10
CONDITION4	100	09	476	0/100	0	
CONDITIONS	100	80	319	0/100	0	25
CONDITIONS	100	100	257	0/100	0	30

 \times ALL ARE PEELED. \triangle SOME ARE PEELED. \bigcirc NONE ARE PEELED.



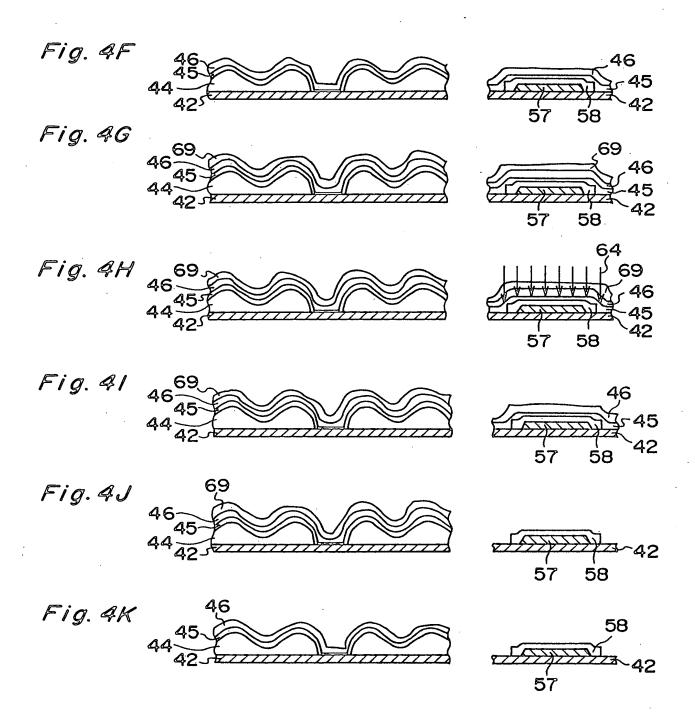


Fig.5

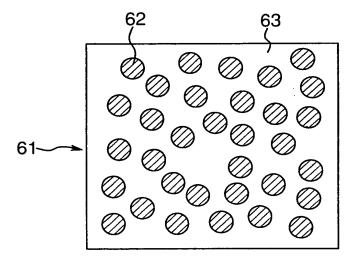


Fig.6

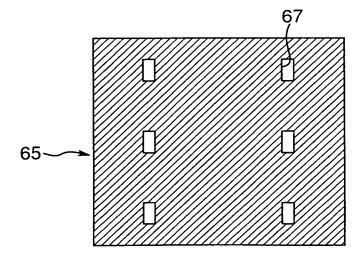


Fig.7

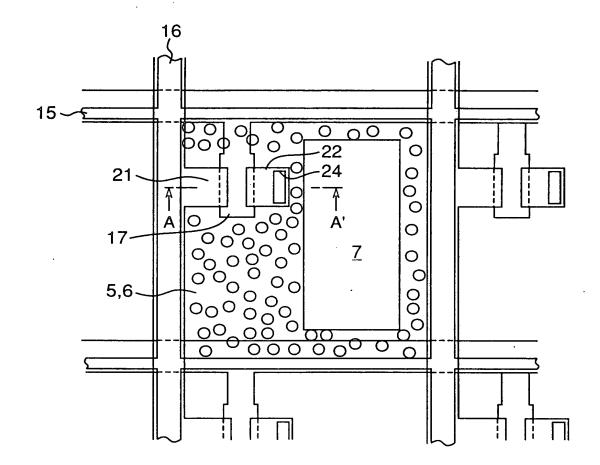
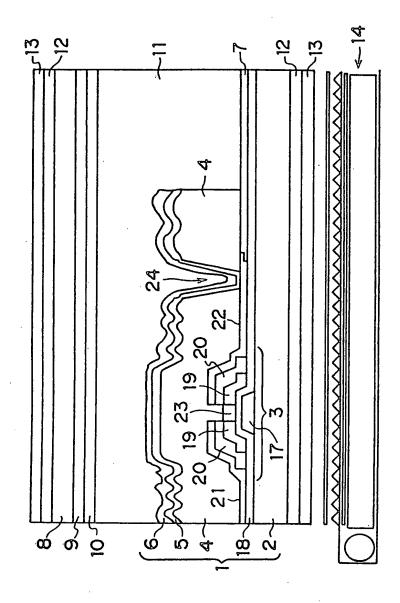


Fig. 8



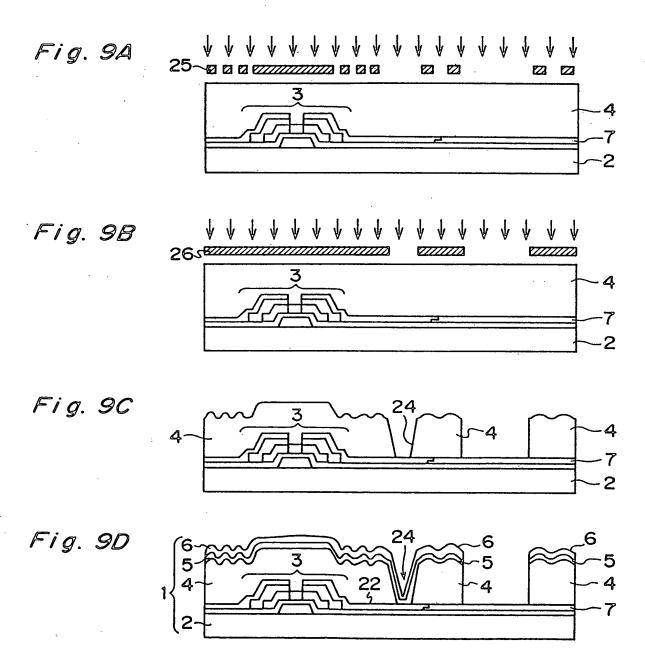


Fig.10

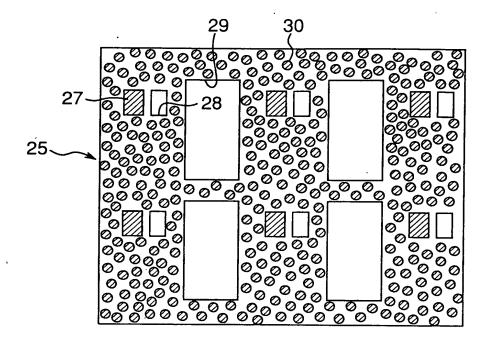


Fig.11

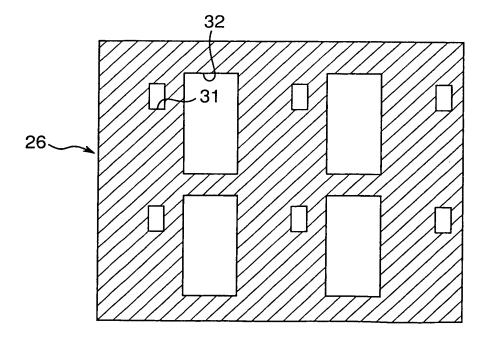


Fig.12

